## IN THE SPECIFICATION

At page 1, please amend the title as follows:

## ELECTRON-EMITTING DEVICE, ELECTRON SOURCE AND METHOD FOR MANUFACTURING IMAGE-FORMING APPARATUS INVOLVING CHANGING A POLYMER FILM INTO AN ELECTROCONDUCTIVE FILM

Please amend the paragraph appearing from page 6, line 22 to page 7, line 26, as follows:

Fig. 1A is a schematic plan view showing an electron-emitting device manufactured by a method according to the present invention;

Fig. 1B is a sectional view along line 1B-1B in Fig. 1A;

Figs. 2A, 2B and 2C are schematic sectional views showing an example of a manufacturing method for a surface conduction electron-emitting device of the present invention;

Fig. 2D represents a light or other illumination source 90 illuminating an electron-emitting device precursor during the manufacturing method;

Figs. 3A, 3B and 3C are schematic sectional views showing another example of an electron-emitting device manufactured by the method according to the present invention;

Figs. 4A, 4B and 4C are schematic sectional views showing a further example of an electron-emitting device manufactured by the method according to the present invention;

Fig. 5 is a schematic view showing an example of a vacuum device having a measurement evaluating function;

Figs. 6A, 6B, 6C, 6D and 6E are schematic views showing an example of steps for manufacturing an electron source having passive matrix arrangement;

Fig. 7 is a schematic view showing an example of a display panel of an image-forming apparatus having passive matrix arrangement and manufactured by a method according to the present invention;

Fig. 8 is a schematic sectional view of a conventional electron-emitting device; and

Fig. 9 is a schematic graph showing an electron-emitting property of the electron-emitting device manufactured by the method according to the present invention.

At page 25, please amend the paragraph appearing at lines 9-20 as follows:

First of all, a surface area 4' of the polymer film 4 subjected to pyrolysis is subjected to the energization operation, thereby forming a gap 5' (Fig. 3B). While the electrons tunneled through the formed gap 5' and are scattered against the opposed surface of the film surfaces of the pyrolytic polymer to emit the electrons, an underlying polymer

area which has not yet been subjected to pyrolysis is gradually subjected to pyrolysis, and, ultimately, the gap 5 is formed through the whole thickness of the polymer membrane 4 (Fig. 3C). Fig. 2D represents a light or other illumination source 90 providing illumination 91 (e.g., light, a laser beam, or electron beam) to a film 4.